Form 1449*

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Applicant: Yong-Jun Hu

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U.S. PATENT DOCUMENTS

*Examiner				-		Filing Date
Initial	Document Number	Date	Name	Class	Subclass	If Appropriate
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<u> TV</u>	_ 4,824,544	04/25/1989	Mikalesen, et al.	204	298	10/29/87
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*Examiner	Document Number	Date	Country	Class	Subclass	Translation Yes No

**Examiner						Translation
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**Examiner Initial	(Including Author, Title, Date, Pertinent Pages, Etc.)					
JN	Clarke, A., "Low-Angle Sidewall Planarization", <u>Semiconductor International</u> , Vol. 18, No. 9, 1, (August, 1995)					
TW	Ogawa, S., et al., "Dependence of Thermal Stability of the Titanium Silicide/Silicon Structure on Impurities", <u>Applied Physics Letters</u> , Vol. 56, No. 8, 725-727, (Feb. 19, 1990)					
JN	Wehner, G.K., "The Aspects of Sputtering in Surface Analysis Methods", Methods of Surface Analysis, Elsevier Scientific, Vol .1, 5-37, (1975)					
24	Wolf, S., et al., "Silicon Processing for the VLSI ERA", <u>Vol. 1, Process</u> <u>Technology, Lattice Press</u> , 367, (1986)					

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Date Considered